Application No.	Applicant(s)	i
10/706,200	FABINSKI ET AL.	
Examiner	Art Unit	
Zia R. Hashmi	2881	*
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	Examiner Zia R. Hashmi ars on the cover sheet with the (OR REMAINS) CLOSED in this or other appropriate communica GHTS. This application is subject and MPEP 1308. the Examiner. der 35 U.S.C. § 119(a)-(d) or (f). been received. been received in Application Not cuments have been received in the entry of this application. atted. Note the attached EXAMIN is reason(s) why the oath or decide to be submitted. on's Patent Drawing Review (Pick Amendment / Comment or in the entry of the header according to 37 CFR 1.1 (sit of BIOLOGICAL MATERIA FOR THE DEPOSIT OF BIOLOGICAL MATERIA FOR THE MATERIA	Examiner Zia R. Hashmi Zia R. Lashimi Zia R. Hashmi Zia R. Lashimi Zia C. Lashimi Zia R. Lashimi Z

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DETAILED ACTION

Allowable Subject Matter

- 1. An "Amendment" was received on August 16, 2004 in response to Office Action of May 21, 2004. Independent claim 1 has been amended, as indicated.
- 2. Claims 1-7 are allowed.
- 3. The following is an examiner's statement of reasons for allowance:

With respect to amended independent claim 1, prior art fails to disclose a method for creating a pattern on a substrate, the method includes the steps of imprinting a first pattern on the substrate; and imprinting a second substantially similar pattern which is intentionally mis-registered in a pre-defined manner with regard to the first pattern so that the combination of the first and second patterns causes a systematic variation in a final size of defined elements across the substrate. Currently, the prior art addresses only the elimination of systematic variations in critical dimension feature size of lithographically defined images, which are sometimes, required to be compensated for process variability in the semiconductor industry. Such techniques, however, are subject to limitation of the mask writing tool address grid, or spot size, when determining the minimum possible difference within a pattern. The present invention overcomes this problem by creating a pattern on a substrate by the method described above. The present invention has the following advantages: varying the feature size in resist across the chip without the artifact of grid-snapping from the mask-writing tool; and the

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incremental difference in feature dimension allowed by this method is so small as to be prohibitive (i.e. very small spot size) with the current mask-writing technology.

Conclusion

4. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments of Statement of Reasons for Allowance".

- 5. Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact Electronic Business Center (EBC) at 866-217-9197 (toll-free).
- 6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Zia Hashmi whose telephone number is (571) 272-2473. The examiner can normally be reached between 8.30 AM- 5 PM. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, John R. Lee can be reached on (571) 272-2477.

Zia Hashmi

September 23, 2004

SSUPERISBARYPANTENT EXAMINER